

A graph showing the relationship between BSE Signal Amplitude (Y-axis) and Detector Output (X-axis). The signal amplitude is constant at a high level for low detector output, then decreases linearly to a minimum, increases linearly to a peak, decreases linearly to a minimum, increases linearly to a peak, decreases linearly to a minimum, and finally increases linearly to a high level for high detector output. This pattern is characteristic of a sawtooth wave.

1(B)

The graph shows the BSE Signal Amplitude on the y-axis and the Detector Output on the x-axis. The curve starts at a constant high level, then dips to a minimum, and finally rises back to the original high level. This dip corresponds to the 'dip' mentioned in the text.

The graph shows the BSE Signal Amplitude on the vertical axis and the Detector Output on the horizontal axis. The signal is a periodic waveform. It starts at a high level, remains constant for a duration T , and then decays exponentially to zero. This pattern repeats.

FIG. 1(C)

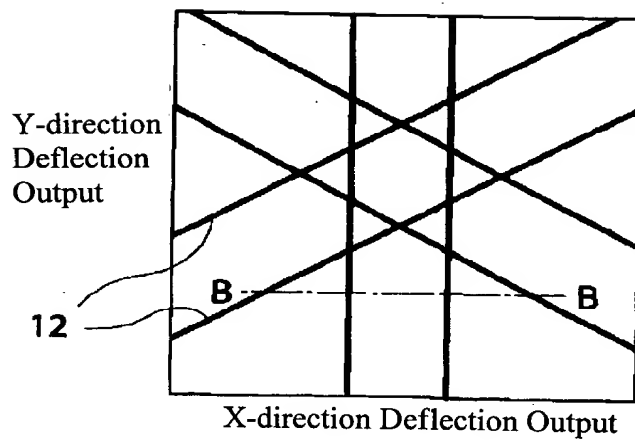


FIG. 2(A)

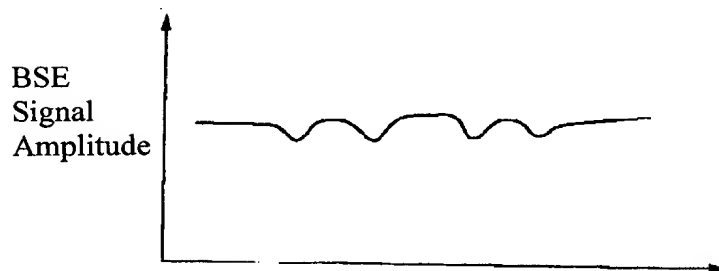


FIG. 2(B)



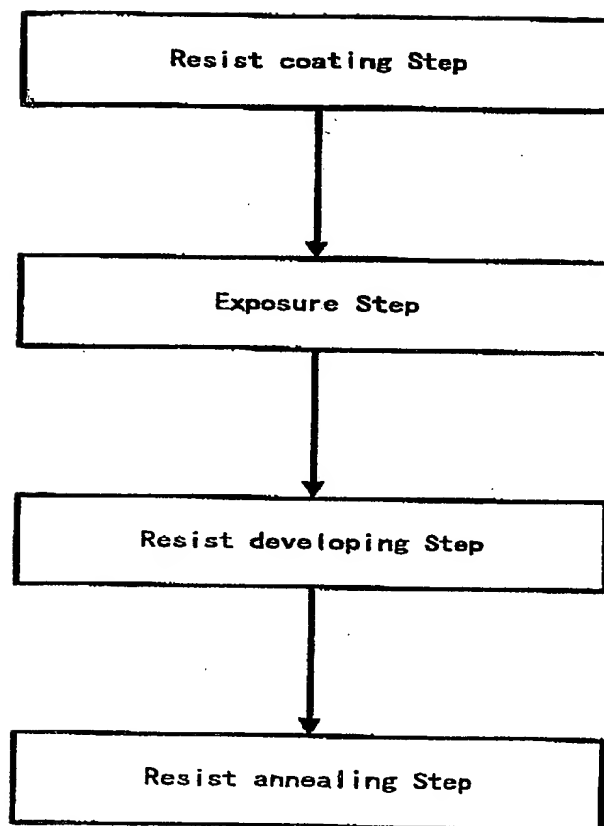
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graph TD
    subgraph Wafer_Production [Wafer Production Step]
        W[WAFER]
    end
    subgraph Mask_Production [Mask Production Step]
        M[Reticle, Mask]
    end
    subgraph Wafer_Processing [Wafer Processing Step]
        direction TB
        subgraph Processing_Techniques [ ]
            direction TB
            CVD
            Sputtering
            Oxidation
            Ion_implantation[Ion implantation]
            Etching
        end
        L[Lithography Step]
        C[Cleaning Step]
        REPEAT([REPEAT])
        REPEAT --> L
        REPEAT --> C
    end
    subgraph Assembly [Assembly Step]
        CH[CHIP]
    end
    subgraph Inspection [Inspection Step]
        direction TB
        SD([Semiconductor Device])
    end

    Wafer_Production --> W
    Mask_Production --> M
    W --> Wafer_Processing
    M --> L
    Wafer_Processing --> Assembly
    Assembly --> CH
    CH --> Inspection
    Inspection --> SD

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FIG. 4



Lithography Step

FIG. 5